AMENDMENTS TO THE CLAIMS

Claim 1 (Currently Amended) A coating solution for use in forming Bi-based ferroelectric thin films that comprises an organometallic compound containing the metallic elements of which a Bi-based ferroelectric thin film is composed, and a compound represented by the following general formula (I):

$$H_3CO - (C_2H_4O)_n - CH_3$$
 (I)

where n is an integer of 2 - 5[[.]],

where A is at least one metallic element selected from among Bi, Pb, Ba, Sr, Ca, Na, K and a rare earth metallic element, and a metal B alkoxide, where B is at least one metallic element selected from among Ti, Nb, Ta, W, Mo, Fe, Co and Cr, as well as at least two dissimilar metal alkoxides selected from among the metal A alkoxide, metal B alkoxide and Bi alkoxide form a composite metal alkoxide.

Claim 2 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to claim 1, wherein said organometallic compound and the compound represented by said general formula (I) (where n is as defined in claim 1) have reacted with each other to form a reaction product.

Claim 3 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to claim 1, which is stabilized with at least one stabilizer selected from among carboxylic anhydrides, dicarboxylic acid monoesters, β -diketones and glycols.

Claim 4 (Original) A coating solution for use in forming Bi-based ferroelectric thin films that comprises an organometallic compound containing the metallic elements of which a Bi-based ferroelectric thin film is composed, and a compound represented by the following general formula (II):

$$(R^1)_3C - CO - CH_2 - CO - C(R^1)_3$$
 (II)

where R^1 is an alkyl group having 1 -3 carbon atoms.

Claim 5 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to claim 4, wherein said organometallic compound and the compound represented by said general formula (II) (where R¹ is as defined in claim 4) have reacted with each other to form a reaction product.

Claim 6 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to claim 4, which is stabilized with at least one stabilizer selected from among carboxylic anhydrides, dicarboxylic acid monoesters, β -diketones and glycols.

Claim 7 (Original) A coating solution for use in forming Bi-based ferroelectric thin films that comprises an organometallic compound containing the metallic elements of which a Bi-based ferroelectric thin film is composed, and a compound represented by the following general formula (III):

$$(R^{1})_{2}C(OH) - C(OH)(R^{1})_{2}$$
 (III)

where R^1 is an alkyl group having 1 - 3 carbon atoms.

Claim 8 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to claim 7, wherein said organometallic compound and the compound represented by said general formula (III) (where R^I is as defined in claim 7) have reacted with each other to form a reaction product.

Claim 9 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to claim 7, which is stabilized with at least one stabilizer selected from among carboxylic anhydrides, dicarboxylic acid monoesters, β -diketones and glycols.

Claim 10 (Original) A coating solution for use in forming Bi-based ferroelectric thin films that comprises an organometallic compound containing the metallic elements of which a Bi-based ferroelectric thin film is composed, and a compound represented by the following general formula (IV):

$$(R^1)_3C$$
 - COOH (IV)

where R¹ is an alkyl group having 1 - 3 carbon atoms.

Claim 11 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to claim 10, wherein said organometallic compound and the compound

represented by said general formula (IV) (where R¹ is as defined in claim 10) have reacted with each other to form a reaction product.

Claim 12 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to claim 10, which is stabilized with at least one stabilizer selected from among carboxylic anhydrides, dicarboxylic acid monoesters, β-diketones and glycols.

Claim 13 (Original) A coating solution for use in forming Bi-based ferroelectric thin films that comprises an organometallic compound containing the metallic elements of which a Bi-based ferroelectric thin film is composed, and a compound represented by the following general formula (V):

$$(R^1)_2C(OH) - CH_2 - CH(OH)R^1$$
 (V)

where R^1 is an alkyl group having 1 - 3 carbon atoms.

Claim 14 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to claim 13, wherein said organometallic compound and the compound represented by said general formula (V) (where R¹ is as defined in claim 13) have reacted with each other to form a reaction product.

Claim 15 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to claim 13, which is stabilized with at least one stabilizer selected from among carboxylic anhydrides, dicarboxylic acid monoesters, β-diketones and glycols.

Claim 16 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to any one of claims 1, 4, 7, 10 and 13, wherein said organometallic compound comprises a Bi alkoxide, a metal A alkoxide, where A is at least one metallic element selected from among Bi, Pb, Ba, Sr, Ca, Na, K and a rare earth metallic element, and a metal B alkoxide, where B is at least one metallic element selected from among Ti, Nb, Ta, W, Mo, Fe, Co and Cr.

Claim 17 (Cancelled)

Claim 18 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to any one of claims 1, 4, 7, 10 and 13, which is intended to form thin films containing Bi-layered structure compounds represented by the following general formula (VI):

$$(Bi_2O_2)^{2+}(A_{m-1}B_mO_{3m+1})^{2-}$$
 (VI)

where A is at least one metallic element selected from among Bi, Pb, Ba, Sr, Ca, Na, K and a rare earth metallic element; B is at least one metallic element selected from among Ti, Nb, Ta, W, Mo, Fe, Co and Cr; and m is an integer of 1 - 5.

Claim 19 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to any one of claims 1, 4, 7, 10 and 13, which is intended to form thin films containing Bi-layered structure compounds represented by the following general formula (VII):

$$Sr_{1-x}Bi_{2+y}(Ta_{2-z}, Nb_z)O_{9+\alpha}$$
 (VII)

where $0 \le x$, y and α , independently ≤ 1 ; and $0 \le z \le 2$.

Claim 20 (Original) The coating solution for use in forming Bi-based ferroelectric thin films according to any one of claims 1, 4, 7, 10 and 13, which is intended to form thin films containing Bi-layered structure compounds represented by the following general formula (VIII):

$$La_{1-x}Bi_{4-y}Ti_3O_{12+\alpha} (VIII)$$

where $0 \le x$, y and α , independently ≤ 1 .

Claim 21 (Currently Amended) The coating solution for use in forming Bi-based ferroelectric thin films according to any one of claims 1, 4, 7, 10 and 13, which [[is]] was converted to a sol-gel fluid by hydrolysis and partial polycondensation using water either alone or in combination with a catalyst.

Claim 22 (Original) A method of forming Bi-based ferroelectric thin films which comprises applying one of the coating solutions of claim 1 onto a substrate, drying the applied coating solution, and then performing a rapid heat treatment at a temperature rise rate of at least 10°C/s to form a Bi-based ferroelectric thin film.